# Optical photon process at XMASS MC simulation

Contract State Sta

#### Current environment

#### GEANT4.9.3

✓ Red Hat Enterprise Linux Server 5.6 (Tikanga)
 ✓ gcc 4.1.2
 ✓ Xeon E5540 x 2 / computer

- **-** 2.53GHz
- 4 core
- ✓ 8GB memory

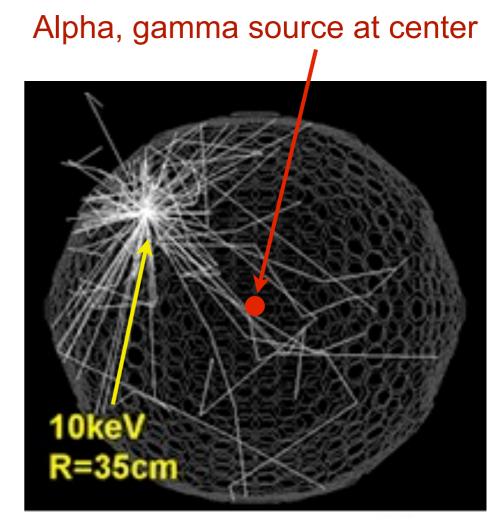
✓ Data size: Background ~1000days 20~30TB

### Optical photon process at XMASS

- In the XMASS detector, scintillation photons from liquid xenon are observed with 642 PMTs.(~15 [photons /keV])
- Need to simulate fine structure of detector.
  - All optical photons are tracked.
  - Process time of optical photons is dominant.

#### **Typical process time (user time by G4Timer)**

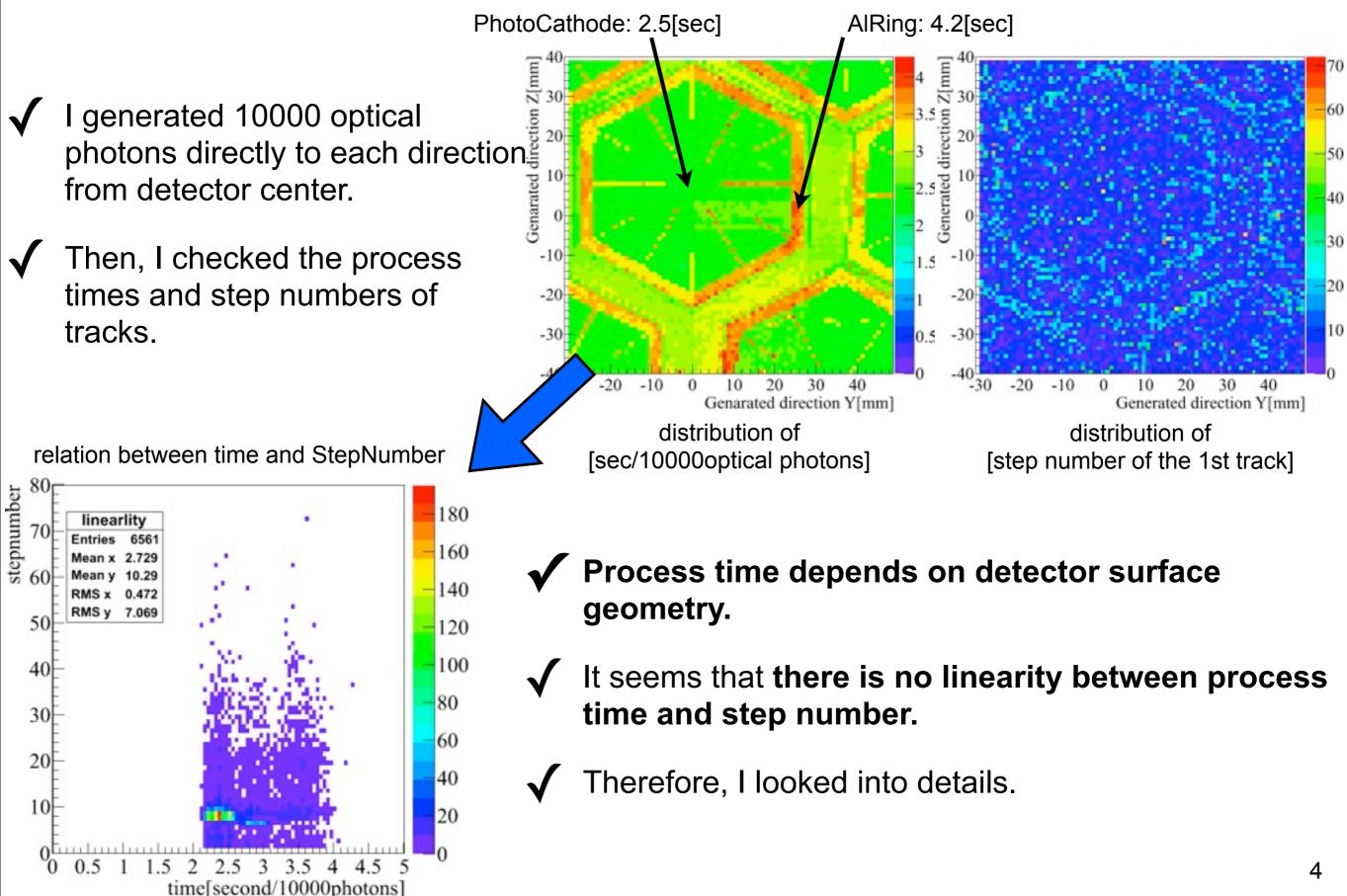
	only optical photons [sec / 10000 photons]	whole process [sec/10000photons]
662keV gamma-ray from detector center	2.6	3.3
<b>1MeV alpha-ray</b> from detector center	2.7	-



A simulation of optical photons in the XMASS detector

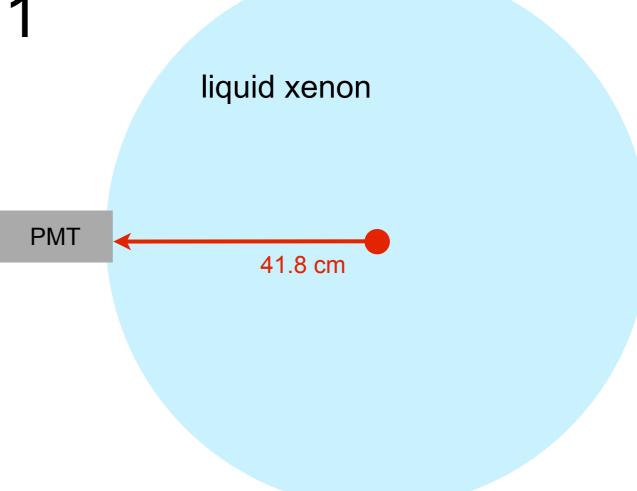
#### Motivation: confirm what requires time so much.

#### UserTime and StepNumber



### Study of process time 1

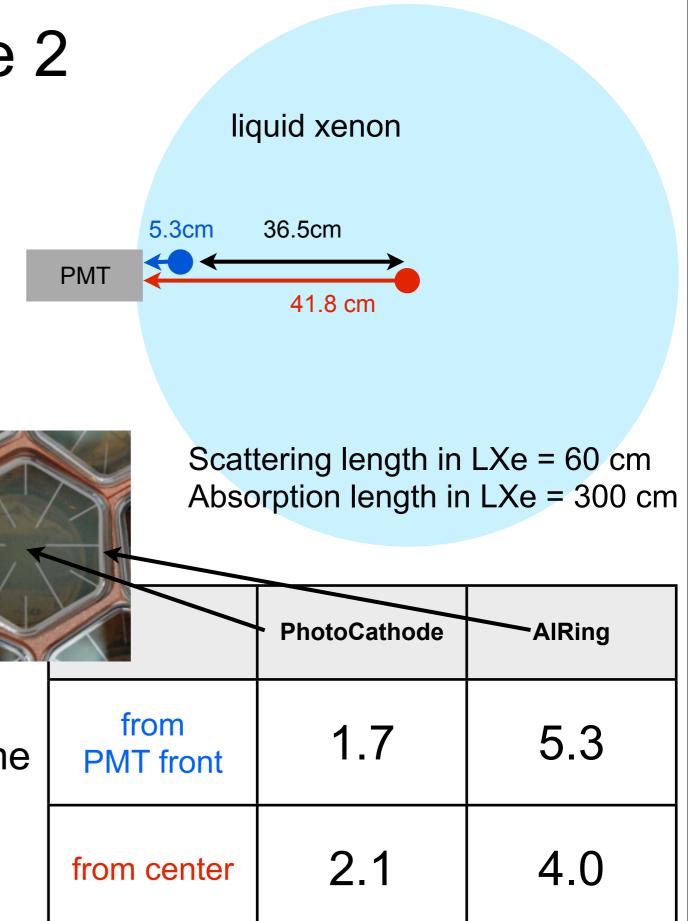
- $\checkmark$  For optical photons process, **GEANT4** transportation sources were modified by Prof.Kurashige.(MOD version)
  - Unnecessary if statements are removed.
- Generate events from center, then compare process times [sec/10000photons].
- Some improvements are observed.
- Use MOD version for further studies.

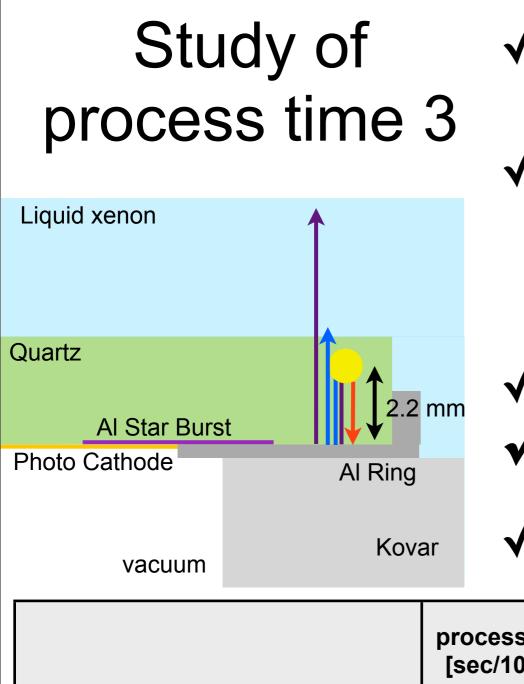


S		Original	MOD
	662keV gamma	2.6	2.4
	1MeV alpha	2.7	2.5
	optical photons to PhotoCathode	2.5	2.1
	optical photons — to AlRing	4.2	4.0
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## Study of process time 2

- In order to check process time in liquid xenon, generated position was moved to just before a PMT window.
- Beamed optical photons to PhotoCathode and AlRing.
  - from detector center
  - from PMT window front
- ✓ By difference between PhotoCathode cases, process time in liquid xenon would be ~0.1[sec/10000/10cm].





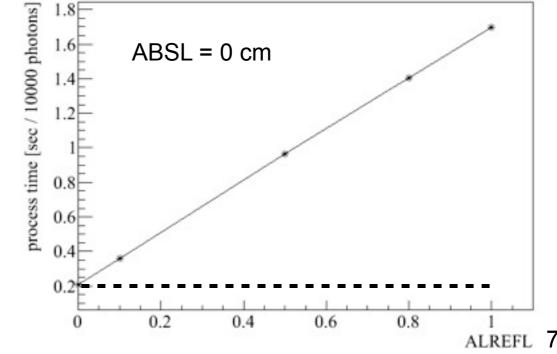
- In order to check process time around reflection at AIRing, generated position was moved to inside PMT quartz window.
- Parameters were changed.
  - LXe absorption length: 0cm, 300cm (original = 300cm)
  - Al reflectance: **0.0 ~ 1.0 (**original = 0.8)

Offset time is ~0.2[s/10000photons].

1.5 [s/10000photons] is required around reflection process at PMT AIRing.(1.7 - 0.2)

Process time after reflection is 2.9[s/10000](4.6 - 1.7).

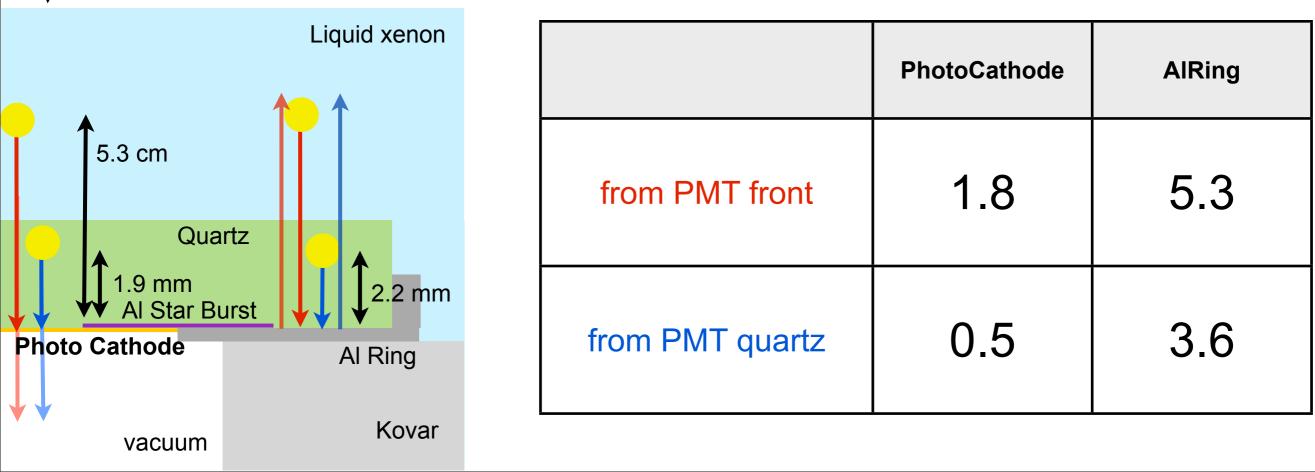
	process time [sec/10000]	mean StepNumber
Al reflectance = 0.0 Absorption length = 0	0.2	1.0
Al reflectance = 1.0 Absorption length = 0	1.7	3.9
Al reflectance = 1.0 Absorption length = 300	4.6	14.5



#### Study of process time 4

- Process time between liquid xenon and PMT quartz window was estimated.
- Beamed optical photons to PMT PhotoCathode and AlRing
  - from inside PMT quartz window , PMT front in LXe
  - Absorption length = 300 cm
    Scattering length = 60 cm
    Al reflectance = 0.8

✓ 1.3 ~ 1.7 [s/10000] seems required for LXe -> PMT quartz process.



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#### Summary

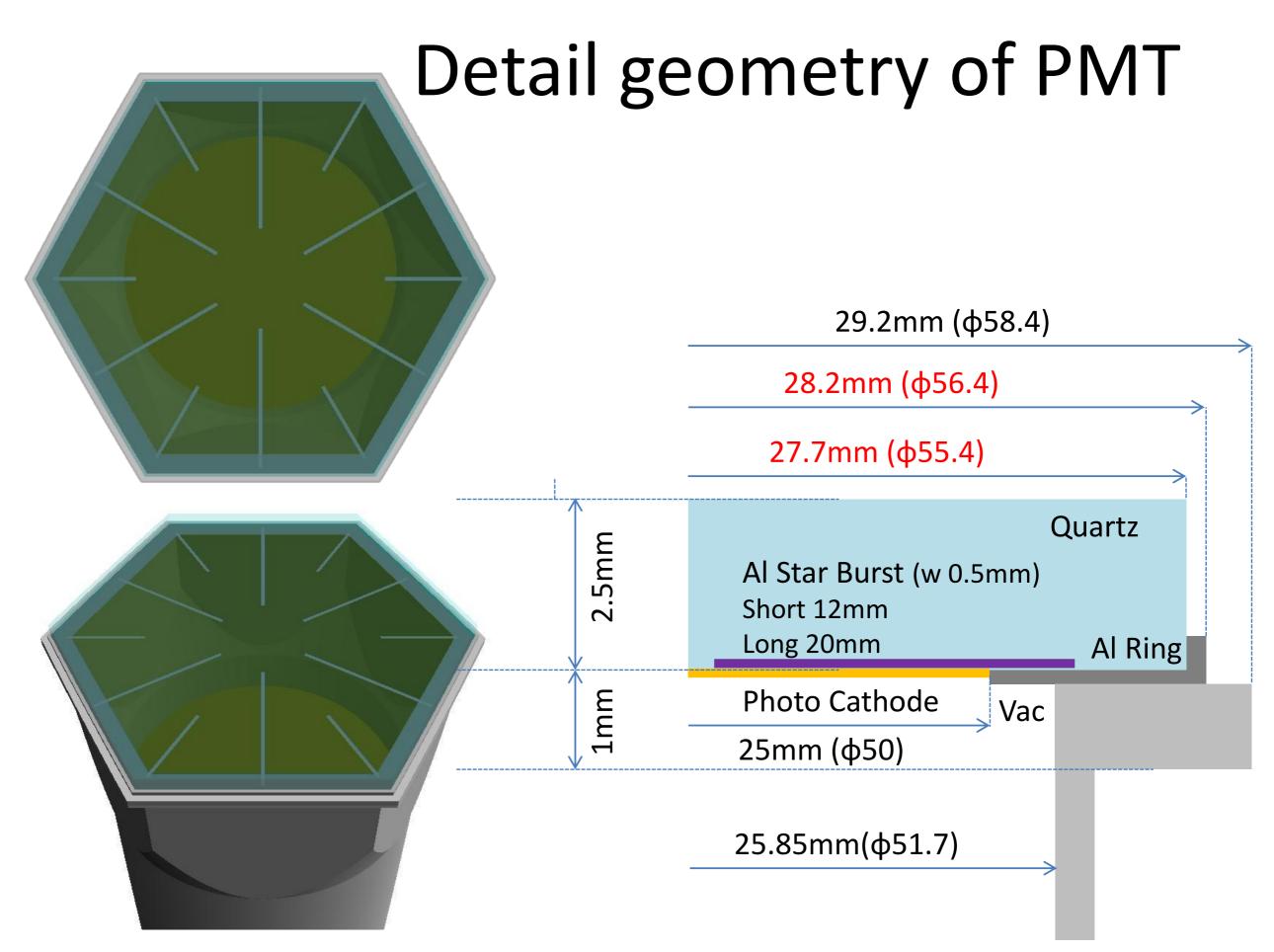
 $\checkmark$  In XMASS simulation, process times of optical photons are investigated.

 $\checkmark$  I used GEANT4 transportation sources modified for optical photons.

- Unnecessary if statements are removed.
- 662 keV gamma: original 2.6 -> MOD 2.4 [s/10000]
- Process times in each step are obtained as follows.
- $\checkmark$  Process 2 looks dominant in XMASS simulation.

Process	time[s/10000photons]
1. Transport in LXe(/10cm)	~0.1
2. LXe -> PMT quartz	1.3 ~ 1.7
3. Reflection at PMT AIRing	1.5
4. After reflection	2.9
5. Offset	~0.2

#### backup



#### Processes and paramters.

- Energy range a few keV ~ some MeV
- Low energy electro magnetic process
  - Photo electric
  - Gamma conversion
  - Compton
  - Ionization
  - Brems
  - Multiple scattering
- Optical photon tracking
  - Absorption
  - Rayleigh Scattering
  - QE tables for each PMT
  - Scintillation
    - Spectrum of scintillation.
    - Non linearity of scintillation efficiency.
  - Refractive index for liquid xenon and quartz.
    - Wavelength dependency
  - Reflection
    - Angle dependence of reflectivity, absorption at photo cathode.